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Introduction

This year's SPIE Conference on Advances in Thin-film Coatings for Optical Applications encompassed a wide range of deposition techniques and an equally wide range of uses for these coatings. The deposition techniques ranged from spin-coating to RF magnetron sputtering to oblique angle physical vapor deposition. The uses ranged from broadband anti-reflection to broadband conductive reflectors to power generation from solar cells.

This was the first year we had high-quality presentations describing the use of thin-films in solar cell applications. It is hoped that this topic will grow in future years along with the use of solar cells themselves. The use of solar cells will inevitably become more widespread as we reduce our dependence on fossil fuels.

I do anticipate that these proceedings will be widely referenced and that readers will be able to discover both important technical details, which will aid their own process development, and new insights which might lead to completely novel applications of thin-film coatings.

It is often said that interesting things occur at interfaces. This is clearly the case where conflicting ideas interface and can be seen in the natural world with the profusion of life found at the interface of land and sea. Likewise, myriad and fascinating phenomena occur at the interface of substrate and optical medium. For this reason, thin-film coatings will remain fertile ground for innovation for the foreseeable future.

I would like to thank the organizers at SPIE who do a wonderful job, and also thank especially, all the contributors. Without your excellent work this conference could not have been a success.

Michael J. Ellison

